

REMARKS

Claims 11-25, 27-40 and 52-60 are pending in this application. Claims 11-22, 52-55 and 60 are withdrawn. By this Amendment, claims 23, 25, 57 and 59 are amended to include the subject matter of claim 26, and claims 26, 56 and 58 are cancelled without prejudice to or disclaimer of the subject matter disclosed therein.

The Office Action rejects claims 23-24 and 56-59 under 35 U.S.C. §102(b) over Mikoshiba et al. (U.S. Patent No. 5,753,320) ("Mikoshiba") and claims 23-40 and 56-59 under 35 U.S.C. §102(e) over Paz de Araujo et al. (U.S. Patent No. 6,110,531) ("Araujo"). Applicant respectfully traverses these rejections.

In particular, Applicant asserts that neither Mikoshiba nor Araujo disclose or suggest a method of fabricating ceramics that includes forming a film forming region having affinity to ceramics to be formed and a non-film forming region having no affinity to ceramics to be formed, to form self-alignably a ceramic film in the film forming region, as recited in independent claims 23, 25, 57 and 59.

Mikoshiba teaches a process for forming a deposited film on a substrate (Abstract), but Mikoshiba is silent about the substrate having a film-forming region and a non film-forming region to form self-alignably a ceramics film in the film-forming region. Accordingly, Applicant asserts that Mikoshiba does not disclose or suggest a method of fabricating ceramics as recited in independent claims 23, 25, 57 and 59.

Araujo teaches using a UV source (Fig. 1, 8) and a deposition chamber 124 in which one or more substrates (6) are held by substrate holder (4) and are subjected to a source of vapor coming from a vaporized source (14). The vaporized source (14) is generated and carried by a carrier gas which may be inert or active, and may contain a catalyst to increase the deposition rate (col. 5, lines 22-30). Araujo is silent about the substrate 117 having a film-

forming region and a non-film forming region to form self-alignably a ceramics film in the film forming region, as recited in independent claims 23, 25, 57 and 59.

In view of their dependence on claims 23 and 25, Applicant asserts that neither Mikoshiba nor Araujo disclose each and every feature of claims 24 and 27-40, including the limitations of claims 23 and 25.

For at least the reasons discussed above, Applicant asserts that neither Mikoshiba nor Araujo disclose or suggest each and every feature of claims 23-25, 27-40, 57 and 59. Moreover, the cancellation of claims 56 and 58 renders their rejection moot. Accordingly, Applicant respectfully requests that the rejections of these claims under 35 U.S.C. §102(b) and §102(e) be withdrawn.

In view of the foregoing, it is respectfully submitted that this application is in condition for allowance. Favorable reconsideration and prompt allowance of the pending claims are earnestly solicited.

Should the Examiner believe that anything further would be desirable in order to place this application in even better condition for allowance, the Examiner is invited to contact the undersigned at the telephone number set forth below.

Respectfully submitted,



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Date: May 14, 2004

Attachment:

Petition for Extension of Time

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